

JP08-166407 (四月) 0.93 0.61 0.92 6.902, 53 ¥U 表面相 最大組み (m m) 0.85 0.650.60 3.30 3.65 6.55 2.30 Kusumoto വധവ 1 些 電解条件 Roughness 最終電圧 謌 先指題 0.6 R \approx 固 5.5 ## 片 度 $(\mathbf{g}/1)$ 20 20 20 30 30 30 30 1 1 雪解液 蹇 FIG.2 Teach an effective roughness and abruptly improved SURFACE ROUGHNESS (μ m) Below $0.4\,\mu$ m, Probe Life This invention CONTACT NUMBER (TIMES) \$DODOO!

 Disclose a probe having a surface roughness of 0.6 μ m

- Not disclose a probe having a surface roughness equal to or less than $0.4~\mu\,\mathrm{m}$.
- Never teach an effective roughness and radius of a tip.

and drive out oxide thin film on metal

pad. Therefore tip can contact with a

conductive layer.

deformation successfully, and break

A spherical tip can occur shear

roughness \leq 0.4 μ m.

10 μ m \leq r \leq 20 μ m

radius

This portion prevents to Conventional a suitable Not make angle FIG.3 Oxide Film Fhis-invention* Suitable angle Electrode Pad

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Suitable radius[r] and roughness

roughness \leq 0.4 μ m

make a shear deformation

successfully,

10 μ m \leq r \leq 20 μ m

of tip

make a lamination stack

Conventional tip
Not make a shear deformation,
Not break and drive out oxide thin film on metal pad.

break and drive out oxide thin film

on metal pad.